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IMPRINT LITHOGRAPHY UTILIZING
ROOM TEMPERATURE EMBOSSING

Abstract of the Disclosure

A method of performing imprint lithography of a surface of a workpiece including a substrate, wherein a stamper/imprinter comprised of a material having thermal expansion characteristics different from the material of said substrate is utilized for embossing a desired pattern in said workpiece surface, the method comprising conducting the embossing at room temperature in order to avoid deleterious effects arising from differences in thermal expansion/contraction characteristics between the stamper/imprinter and the workpiece which occur during conventional imprinting at elevated temperatures. Embodiments of the invention include forming servo patterns in disk-shaped substrates utilized in the manufacture of hard disk magnetic recording media.